

PATENT NUMBER

U.S. UTILITY Patent Application

O.L.P.E.

PATENT DATE

FA
SCANNED A.G. 3 O.A. 11/2

APPLICATION NO. 09/882741	CONT/PRIOR D	CLASS 136 450	SUBCLASS 700	ART UNIT 1765	EXAMINER Umez-Khouri
APPLICANTS Yiglon Wang Maichang Li Shaoher Pan					
TITLE Method of etching high aspect ratio openings in silicon					

PTO-2000
 1259

ISSUING CLASSIFICATION[illegible]

<input type="checkbox"/> TERMINAL DISCLAIMER	DRAWINGS		CLAIMS ALLOWED	
	Sheets Draw.	Figs. Draw.	Total Claims	PAYOR OF P.O.C.
<input type="checkbox"/> The term of this patent subsequent to _____ (date) has been disclaimed.			NOTICE OF ALLOWANCE MAILED	
	(Assistant Examiner)	(Date)		
<input type="checkbox"/> The term of this patent shall not extend beyond the expiration date of U.S. Patent No. _____ _____			ISSUE FEE	
	(Primary Examiner)	(Date)	Amount Paid	Balance Due
<input type="checkbox"/> The terminal _____ months of this patent have been disclaimed.			ISSUE BATCH NUMBER	
	(Legal Inventions Examiner)	(Date)		

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(continued on page 10)

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